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**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q51885

Akitaka KIMURA

Appln. No.: 09/161,981

Group Art Unit: 2812

Confirmation No.: 8269

Examiner: J. Davie

Filed: September 29, 1998

For: SEMICONDUCTOR LAYER FORMED BY SELECTIVE DEPOSITION AND  
METHOD FOR DEPOSITING SEMICONDUCTOR LAYER

**AMENDMENT UNDER 37 C.F.R. § 1.111**

**MAIL STOP AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated March 24, 2004, please amend the above-  
identified application as follows on the accompanying pages.

**TABLE OF CONTENTS**

AMENDMENTS TO THE CLAIMS .....	2
REMARKS .....	9